

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant	: Masaharu Nagai et al.	Art Unit	: 1756
Serial No.	: 10/694,986	Examiner	: Daborah Chacko Davis
Filed	: October 29, 2003	Conf. No.	: 5334
Title	: METHOD FOR REMOVING RESIST PATTERN AND METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICE		

**MAIL STOP AF**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

AMENDMENT IN REPLY TO ACTION OF MAY 11, 2006

Please amend the above-identified application as follows:

**Amendments to the Claims** begin on page 2.

**Remarks** begin on page 7.